



00862.022170

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: )  
Haruhito ONO et al. ) : Examiner: D. A. Vanore  
Application No.: 09/819,907 ) : Group Art Unit: 2881  
Filed: March 29, 2001 ) : Confirmation No.: 5369  
For: ELECTRON OPTICAL SYSTEM, ) : December 16, 2003  
CHARGED-PARTICLE BEAM EXPOSURE :  
APPARATUS USING THE SAME, AND )  
DEVICE MANUFACTURING METHOD :  
)

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT

Sir:

In response to the Official Action dated September 16, 2003, please amend the above-identified application as follows:

12/18/2003 MAHMED1 00000119 09819907  
02 FC:1201 172.00 0P